

Form PTO-1449

Sheet _____ of _____

INFORMATION DISCLOSURE CITATION
IN AN APPLICATION

(Use several sheets if necessary)

Docket Number (Optional)

Application Number

HNP 201

10/55-3, 728

Application

KAROLA RICHTER ET AL

Fullar Date

1/3/2006

Group Art Unit

176.5

U.S. PATENT DOCUMENTS

[illegible]

FOREIGN PATENT DOCUMENTS

[illegible]

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

[illegible]

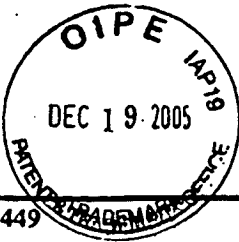
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DATE CONSIDERED

11/30/2007

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.



Sheet 1 of 4

Application Number

10/553,728

RICHTER et al

10/14/05

Group Art Unit

(Use several sheets if necessary)

[illegible]

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO
IPG/	0 8 1 8 6 0 9 5	07/16/96	JAPAN	H01L	21/3065		
IPG/	0 4 0 2 8 2 2 9	01/30/92	JAPAN	H01L	21/3205		

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PGI	ZIJLSTRA, et al. "Fabrication of two-dimensional photonic crystal waveguides..." J. Vac. Sci. Technol. B 17(6) Nov/Dec 1999 pp. 2734-2739
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/Patricia George/

08/23/2007

Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Group Art Unit

[illegible][illegible]

IPG/	VOLLAND et al. "DRY ETCHING WITH GAS CHOPPING ..."
	J. VAC. Sci. Technol. B 17 (6) Nov/Dec 1999 pp 2768-2771
IPG/	BOEING, "Fundamentals of Plasma Chemistry and Technology"
	The Research Institute of Plasma Chemistry, Canby, CA, p. 174
IPG/	CHANG et al, "Highly selective etching for polysilicon..."
	J. Appl. Phys 80 (5), 1 September 1996 pp 3048-3055

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Applicant

RICHTER at al.

Filing Date

Group Art Unit

Sheet 1 of 3
30/553728

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
IPG/	61198150	03/08/01	GELZINIS	H01L	29/00	
IPG/	6180466	01/30/01	IBOK	H01L	21/336	

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO
IPG/ 1	9736370	03/04/99	GERMANY	H01L	21/365		
IPG/	4241045	05/26/94	GERMANY	C27F	4/00		
IPG/	0822582	02/04/98	EPO	H01L	21/306		

OTHER DOCUMENTS

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IPG/	A VOLLAND B et al; "Dry etching with gas chopping without rippled sidewalls"; JOURNAL OF VACUUM SCIENCE & TECHNOLOGY, B: MICROELECTRONICS AND NANOMETER STRUCTURES, NOVEMBER 1999 VOLUME 17, ISSUE 6, PAGES: 2768-2771					

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JC20 Rec'd PCT/PTO 14 OCT 2009

PTO/SB/08 (2-92)

Sheet 2 of 3

Form PTO-1449 INFORMATION DISCLOSURE CITATION IN AN APPLICATION <i>(Use several sheets if necessary)</i>	Docket Number (Optional) HMP 201	Application Number 2007553728
Applicant RICHTER et al		Filing Date
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U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS *(Including Author, Title, Date, Pertinent Pages, Etc.)*

/PG/		J. P. JOHN et al.; J. ELECTROCHEM SOC. Vol. 140 No. 9 (1993) pp 2622-2625
/PG/		H. SEIDEL et al.; J. ELECTROCHEM SOC., Vol. 137, No. 11, November 1990, pp 3612-3632
/PG/		B. KIM et al.; J. ELECTROCHEM SOC. Vol. 145, No. 7 July 1998, pp 2498-2508

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FOREIGN PATENT DOCUMENTS

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						YES	NO

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	p. 174, The Research Institute of Plasma Chemistry, Carlsbad, CA
/PGI/	J. W. RANGELOW et al; J. VAC. SCI. TECHNOL, B13(6)
	Nov/Dec 1995, pp 2394-2399
/PGI/	K. M. CHANG et al; JOURNAL OF APPLIED PHYSICS
	SEPT 1, 1996, Vol. 80, Issue 5, pp 3048-3055

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